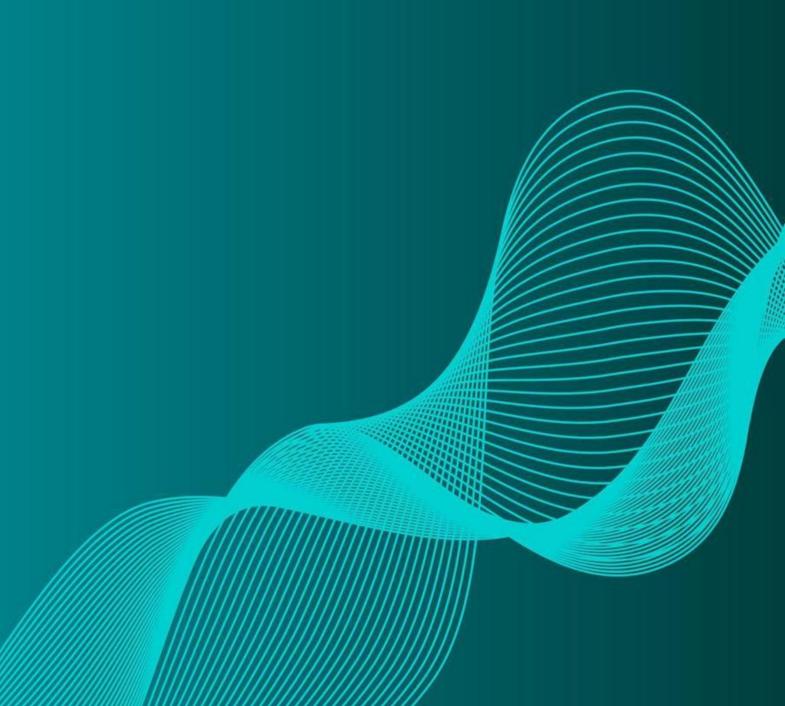


## WALOT

WAfer Level Optics Tester Fully Automated



### The Challenge of Wafer-Level Optical Testing

Wafer-level testing of passive optical components such as diffractive optical elements (DOE), meta optical elements (MOE) and micro lens array (MLA), presents a set of unique challenges. The use of these optical elements ranges industries such as consumer electronics, automotive, and telecommunications. As these components become more integral to advanced

technologies - like facial recognition in smartphones, light projection in vehicles, and signal transmission in optical fiber networks - the scalability of testing process becomes a critical challenge: manufacturers need to catch defects as early as possible in the production process, balancing the need for high accuracy and repeatability with a high throughput.

## WALOT™: the fully Automated Wafer-Level Test Systems

At Alfamation we offer a fully automated test system designed to combine efficient automation with the capability of handling a wide range of functional tests. The platform is equipped with a high performative and reliable air-bearing wafer handling system combined with a flexible measurement setup architecture which requires little to no maintenance. With features like wafer warpage compensation, vacuum holding mechanisms and customizable chuck frames, it is possible to fully handle any kind of wafer. 0 0 alfamation

#### WALOT™ Key Features and Benefits

- Off-the-Shelf Automated Platform: boost productivity with standard options or configurable builds to meet specific needs
- Wide Configurability: modular approach used to equip the system with different instruments configurations allowing to test different type of devices
- High Test Coverage: one platform with multiple test capabilities
- Multiple Chuck Compatibility: test different wafers with different shapes and layouts
- **Singulated Devices Test**: through the use custom-designed tray, the platform can test singulated devices as well
- Wafer Warpage Compensation: through a tip-tilt motion system
- Automated Loading Options: the platforms can either be stand-alone, manually loaded by operators, or integrated in the assembly line through an additional wafer handler unit
- Powered by Alfamation Supernova<sup>™</sup>: based on the testing industry standard sequencer NI TestStand, it provides a fully programmable automatic test sequence



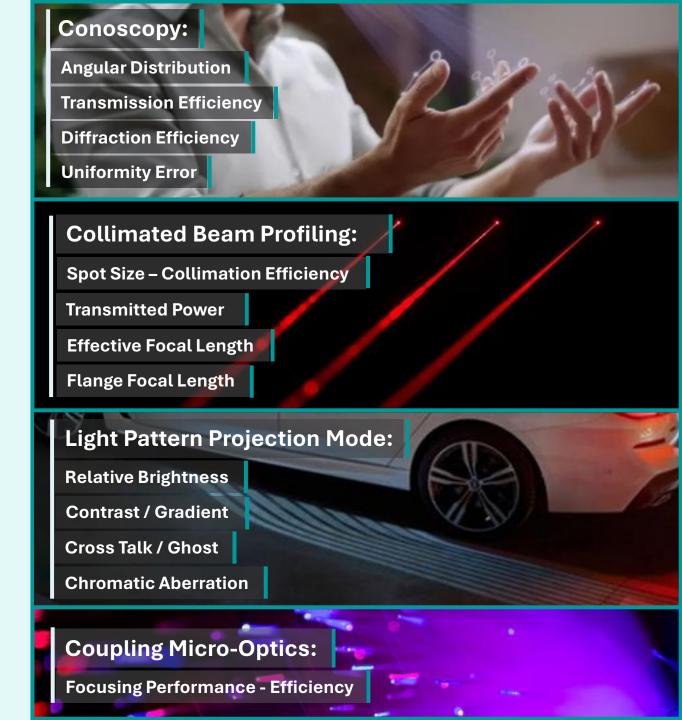
Platform Specifications	
XY Wafer Positioning Accuracy, Repeatability (3σ)	±5 um/m, ±0.3 um
Maximum Wafer Diameter	Up to 12 inch
Dimensions W-D-H	1250-1150-1100 mm
Weight	800 kg
Air Pressure	6.5 – 8 bar
Flow rate	30 L/min
Air pressure humidity – Dew Point	Maximum temperature: 0°C Ideal temperature < -20°C

# Comprehensive Testing Capabilities for Complete Optical Characterization

The WALOT™ platform offers a comprehensive and scalable solution for the many challenges associated with wafer-level optics testing across a board spectrum of industries. The system can thus be tooled in different configurations to test specific devices. Some of the configurations for the WALOT™ system are:

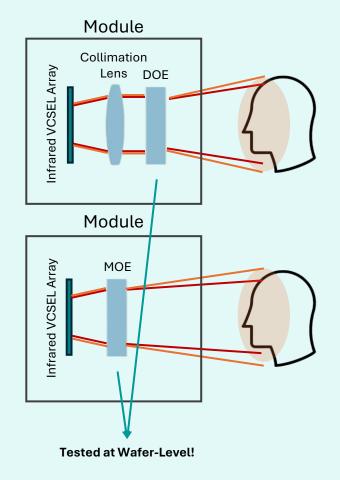
- Conoscopy Mode
- Collimated Beam Profiling Mode
- Light Pattern Projection Mode
- Coupling Micro-Optics Mode

These are just some of the possible configuration of tester setup: the flexibility of our solution allows to test multiple kinds of device, so you can reach out to Alfamation to integrate your specific test needs within our platform!



## Conoscopy Mode: DOEs and MOEs testing

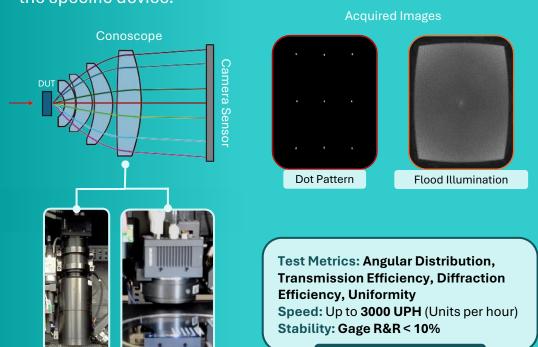
**Diffractive optical elements (DOE), meta optical elements** (**MOE**) are all widely used components in consumer electronics, for **face ID and gesture recognition**.



DOEs and MOEs are used for both Dot Pattern Projection (red) and Flood Illumination (orange) in the face id and gesture recognition procedure.

## **Conoscopy Mode: Test Principle and Configuration**

To characterize this kind of devices, the tester is equipped with a high-resolution camera and a specialized optics called Conoscope. This lens system has a high acceptance angle and produces an angular map of the light emitted by the device on the camera sensor. The device is typically illuminated with a single spot laser source. The properties of the beam depend on the specific device.



145°

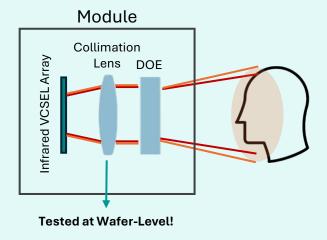
105°

Different conoscopes design for different needs!

**Performance** 

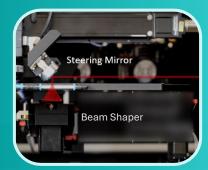
# Collimated Beam Profiling Mode: Collimation Lenses testing

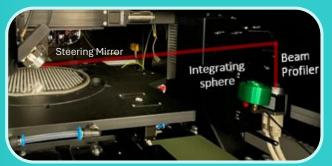
**Collimation Lenses** are components used in a very wide range of applications. In consumer electronics, they are often paired with DOEs for **face ID** and **gesture recognition**.



# Collimated Beam Profiling Mode: Test Principle and Configuration

These devices are typically illuminated with a **single spot divergent** laser source. The tester is equipped with a **distance sensor**, used to characterize the wafer warpage. A scan is then performed by moving the light source: the goal is placing the beam waist at the focal distance from the collimation lens. The resulting collimated beam is deviated by a **steering mirror** towards a **camera sensor** and an **integrating sphere**.





Test Metrics: Spot Size, Transmitted Power, Flange Focal Length, Effective Focal Length

Speed: Up to 1500 UPH (Units per hour)

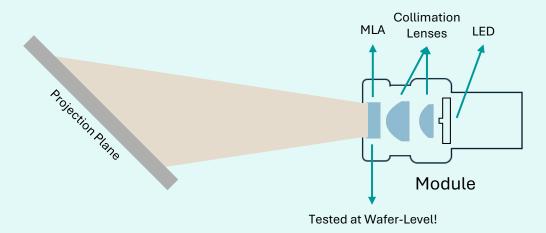
Stability: Gage R&R < 10%

Spot on Beam Profiler

**Performance** 

#### Light Pattern Projection Mode: Micro Lens Arrays (MLAs) testing

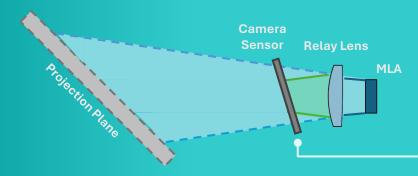
Micro Lens Arrays (MLAs) are used in the automotive industry for vehicle light projection. They are employed for both decorative lighting purposes (welcome carpet or dashboard illumination) and headlights.



A LED mounted on a PCB shines light on a system of collimation lenses. The resulting signal gets to the MLA, which projected a pattern on a target projection plane (i.e. street, dashboard, ...). The projection surface is can be from 500 mm to tens meters away from the device, and the projected area can range from 0.5 to a few meters too.

#### Light Pattern Projection Mode: Test Principle and Configuration

Due to the dimension of the working distance and illuminated area of the device, to keep the test environment compact, Alfamation designed a **relay lens system**, which allows to get the information needed for the test on a relatively small **camera sensor**. The MLA is usually illuminated with a **LED** and the specific properties of the beam hitting the device can be adjusted based on the specific test needs.



Test Metrics: Relative Brightness,
Contrast\Gradient, Cross Talk\Ghost,
Chromatic Aberration

Speed: Up to 2800 UPH (Units per hour)

Stability: Gage R&R < 10%

Performance



Projection on Camera Sensor

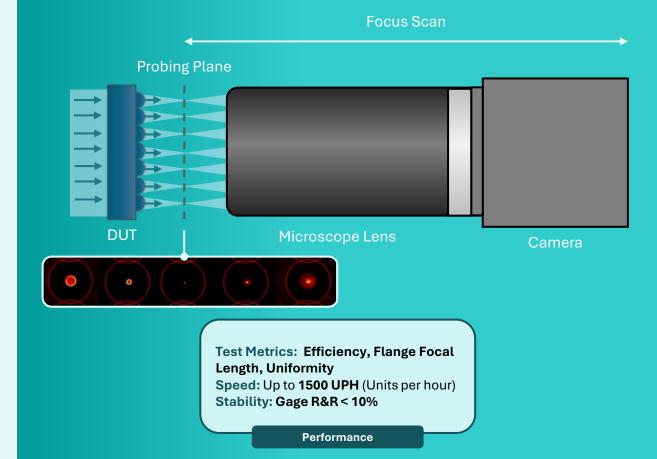
## Coupling Micro-Optics Mode: Telecom and Imaging optics testing

**Coupling optics** are often used in telecommunication industry and for imaging purposes.



#### Coupling Micro-Optics Mode: Test Principle and Configuration

These lenses or array of lenses are usually illuminated by a laser beam. A **microscope lens** is used to collect the signal coming out of the devices: a **focus scan** is performed to minimize the resulting spot sizes on **a high-resolution camera sensor**.



### Powered by SUPERNOVA...

**Variants Management:** Single control panel for management of all variants

**Resources Management:** Panel with all HW resources

**Application development:** Graphic management of test recipe; easy integration of customer libraries

**Results Management:** SQL DB for limits/results

storage and analysis

Integrated software version management
Over 2'000 Active Licences



#### **Powered by**

### TUNETRON

- Analyse test stability & repeatability
- Analyse test time
- Correlate test results

DCS LTE C/N -A 53:  DCS LTE AGC -A 53:  DCS LTE C/N -A 53:  DCS LTE EstSen 53:											
DCS LTE C/N -A 53		N 1	127	-40	0	-17.674960629	0.8521	MainSequence.CELLU	4.82	7.824	6.914
	00 PRODUCTION	N 1	127	-33	-27	-31.853543307	0.21074	MainSequence.CELLU	0.66	4.745	1.813
DCS LTE EstSen 53	20 PRODUCTION	N 1	127	-40	0	-17.136299212	0.76013	MainSequence.CELLU	4.44	8.77	7.515
	10 PRODUCTION	N 1	127	-90	-50	-68.865748031	0.81925	MainSequence.CELLU	1.19	8.138	7.676
DCS LTE AGC -A 53	00 PRODUCTION	N 1	127	-35	-29	-33.036220472	0.19787	MainSequence.CELLU	0.6	5.054	3.308
DCS LTE C/N -A 53	20 PRODUCTION	N 1	127	-40	0	-17.559685039	0.83302	MainSequence.CELLU	4.74	8.003	7.027
DCS LTE EstSen 53	10 PRODUCTION	N 1	127	-90	-50	-68.482992125	0.86449	MainSequence.CELLU	1.26	7.712	7.127
LTE TX EVM - A 51			127	-50	-17	-35.044722277	2.55728	MainSequence.CELLU	7.3	2.151	1.949
LTE TX AvOP 514			127	-11.9	-5.9	-10.448897637	0.17265	MainSequence.CELLU	1.65	5.792	2.802
LTE TX AVOP IS 54			127	-78	-50	-58.151102362	0.35782	MainSequence.CELLU	0.62	13.042	7.593
LTE TX AVOP IS 54			127	-78	-50	-60.957952755		MainSequence.CELLU		17.476	13.679
LTE TX AVOP IS 54			127	-68		-45.135590551		MainSequence.CELLU		19.628	7.2
LTE TX EVM - A 51			127	-50	-17	-35.010345138	2.91696	MainSequence.CELLU	8.33	1.886	
LTE TX AvOP 514			127	-12.6	-6.6	-10.339212598		MainSequence.CELLU	1.23	7.857	5.921
LTE TX AvOP IS 54	90 PRODUCTION	N 1	127	-58	-30	-33.195039370	0.18336	MainSequence.CELLU	0.55	25.451	5.808
120 100 80 40 20 -47.49		-45.992 lasses [FCT_dBm]	-45.239	-44.485	Value [FCT_dBm]	-44.713 -45.135 -45.135 -46.138 3σ (-47.562)	20	40 60 Rep	80 10 petitions		140
Chart Repetitions +3σ (261935.	032)	Chart I	A v	s - BTLE Malue	10dIndD f 262707.9 2	anner .	- WLAN_	BT_1			

Repetitions

Cpk/Ppk





#### Install your **System** Worldwide

Alfamation has been installing test solutions worldwide for more than 30 years.

**EMEA**: France, Germany, Italy, Portugal, Poland, Czech R., Slovakia, Spain, Belgium, Hungary, Romania, Egypt

Americas: Brazil, Canada, Mexico,

USA

Asia: China, HK, Indonesia, Malaysia, Singapore, Korea,

Taiwan, Thailand



#### **Get Support Everywhere**

Alfamation has its HQ in Italy and can easily provide support around Europe. An additional office in Suzhou (China) provide service all over Asia.

As a part of InTest Corporation, Alfamation has also access to a network of support which ranges worldwide.

